



ELSEVIER



Integration, the VLSI Journal 2018 Best Paper Award

Awarded to:

Yíbo Lín, Bei Yu, Yí Zou, Zhuo Lí, Charles J. Alpert and David Z. Pan

For the paper entitled:

Stitch aware detailed placement for multiple e-beam lithography

Volume 58, Pages 47-54

*Dr. Sheldon Tan
Editor-in-Chief
Riverside, USA*

*Dr. Xin Li
Special Content Editor
Durham, USA*

*Dr. Telli Faez
Publisher in Computer Sciences
Elsevier, Netherlands*